

Notice of References Cited	Application/Control No. 10/660,602		Applicant(s)/Patent Under Reexamination MOORE, JOHN T.	
	Examiner Christian Wilson		Art Unit 2824	Page 1 of 1

U.S. PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
*	A	US-6,487,106	11-2002	Kozicki, Michael N.	365/153
*	B	US-RE37,259	07-2001	Ovshinsky, Stanford R.	365/163
*	C	US-5,714,768	02-1998	Ovshinsky et al.	257/40
*	D	US-6,569,705	05-2003	Chiang et al.	438/95
*	E	US-5,920,788	07-1999	Reinberg, Alan R.	438/466
	F	US-			
	G	US-			
	H	US-			
	I	US-			
	J	US-			
	K	US-			
	L	US-			
	M	US-			

FOREIGN PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
	N					
	O					
	P					
	Q					
	R					
	S					
	T					

NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)			
	U	Dikova <i>et al.</i> , Influence of the microstructure on the photoinduced transformations in vacuum deposited As ₂ S ₃ thin films, <i>Vacuum</i> , 58 (2000) 490.			
	V	Cerrina, F., Lithography, <i>Wiley Encyclopedia of Electrical and Electronics Engineering Online</i> , (John Wiley & Sons) Dec. 1999.			
	W				
	X				

*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
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